



# Liquid Chemicals Global Technical Committee Japan TC Chapter

## Meeting Summary and Minutes

June 18, 2021

15:00 – 17:00

SEMI Japan office, Tokyo

### TC Chapter Announcements

*Next TC Chapter Meeting*

December 3<sup>rd</sup>, 10:00-12:00

SEMI Japan office, Tokyo

### Table 1 Meeting Attendees

*Italics indicate virtual participants*

**Co-Chairs:** Hiroshi Tomita (KIOXIA), Hiroyuki Araki (SCREEN Semiconductor Solutions)

**SEMI Staff:** Hirofumi Kanno

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
<i>FEMTO Deployments Inc.</i>	<i>Nakanishi</i>	<i>Yukiko</i>	<i>AIST</i>	<i>Kato</i>	<i>Haruhisa</i>
<i>ADVANCE ELECTRIC</i>	<i>Sasao</i>	<i>Kimihito</i>	<i>SCREEN Semiconductor Solutions</i>	<i>Araki</i>	<i>Hiroyuki</i>
<i>Nihon Entegris</i>	<i>Nagafuchi</i>	<i>Takuya</i>	<i>Rion</i>	<i>Kondo</i>	<i>Kaoru</i>
<i>Nihon Pall</i>	<i>Takakura</i>	<i>Tomoyuki</i>	<i>X-FAB Sarawak Sdn. Bhd</i>	<i>Emily</i>	<i>Liew</i>
<i>Organo</i>	<i>Sugawara</i>	<i>Hiroshi</i>	<i>Nihon Pall</i>	<i>Tsuzuki</i>	<i>Shuichi</i>
<i>SCREEN Semiconductor Solutions</i>	<i>Fujitani</i>	<i>Yoshiyuki</i>	<i>KIOXIA</i>	<i>Tomita</i>	<i>Hiroshi</i>
			<i>SEMI Japan</i>	<i>Hirofumi</i>	<i>Kanno</i>

### Table 2 Leadership Changes

None

### Table 3 Committee Structure Changes

None

### Table 4 Ballot Results

None

### Table 5 Activities Approved by the GCS between meetings of the TC Chapter

None

**Table 6 Authorized Activities**

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	Type	SC/TF/WG	Details
6820	SNARF	Trace Metal Analysis for High Pure IPA TF	New Standard: Guide for Trace Iron Analysis in High Purity IPA

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

**Table 7 Authorized Ballots**

None

**Table 8 SNARF(s) Granted a One-Year Extension**

None

**Table 9 SNARF(s) Abolished**

**Table 10 Standard(s) to receive Inactive Status**

None

**Table 11 New Action Items**

None

**Table 12 Previous Meeting Action Items**

None

**1 Welcome, Reminders, and Introductions**

Hiroyuki Araki (SCREEN Semiconductor Solutions) called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

**Attachment:** 1 SEMI Standards Required Elements\_June2020\_E+J

**2 Review of Previous Meeting Minutes**

The TC Chapter reviewed the minutes of the previous meeting.

**Motion:** Approve the minutes as written

**By / 2<sup>nd</sup>:** Takuya Nagafuchi / Nihon Entegris K.K., Tomoyuki Takakura / Nihon Pall Ltd.

**Discussion:** The name should be changed from Futatsuki to Sugawara.

**Vote:** 10:0 Pass

**Attachment:** 2 LC Minutes\_2021.01.29v1.0

### 3 Liaison Reports

#### 3.1 *Liquid Chemicals North America TC Chapter*

Hirofumi Kanno (SEMI) reported for the NA TC Chapter.

**Attachment:** 3 NA LC Liaison Jan

#### 3.2 *SEMI Staff Report*

Hirofumi Kanno (SEMI) gave the SEMI Staff Report.

**Attachment:** 4 Staff Report April 2021\_v1

### 4 Ballot Review

None

### 5 Subcommittee and Task Force Reports

#### 5.1 *Liquid Filter TF*

Tomoyuki Takakura (Nihon Pall) reported for the Task Force. The TF meeting was held last week, and we are continuing to discuss the test procedure.

#### 5.2 *Liquid-Borne Particle Counter TF - No Report*

#### 5.3 *Diaphragm Valve TF - No Report*

#### 5.4 *Welding Fitting TF - No Report*

#### 5.5 *Trace Metal Analysis for High Pure IPA TF*

Kimihito Sugawara (Organo) reported for the Task Force. TF meetings have not been held recently, but the TF submits the new SNARF for New Standard: Guide for Trace Iron Analysis in High Purity IPA

**Motion:** SNARF Approval for New Standard: Guide for Trace Iron Analysis in High Purity IPA  
Motion: Approve the SNARF for New Standard: Guide for Trace Iron Analysis in High Purity IPA

**By / 2<sup>nd</sup>:** Hiroshi SUGAWARA / Organo Corporation, Takuya Nagafuchi / Nihon Entegris K.K.

**Discussion:** None

**Vote:** 10:0

**Attachment:** 5 SNARF\_1

### 6 Old Business

None

### 7 New Business

#### 7.1 *Japan Liaison Report Update for Next NA Liquid Chemicals Committee meeting*

### 8 Next Meeting and Adjournment

The next meeting is scheduled for December 3<sup>rd</sup> 10:00-12:00 at SEMI Japan office, Tokyo. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: 16:30.

Respectfully submitted by:

Hirofumi Kanno



SEMI Japan

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Email: hkanno@semi.org

Minutes tentatively approved by:

<Name> (<Company>), Co-chair	<Date approved>
<Name> (<Company>), Co-chair	<Date approved>

**Table 13 Index of Available Attachments<sup>#1</sup>**

<i>Title</i>	<i>Title</i>
1 SEMI Standards Required Elements_June2020_E+J	2 LC Minutes_2021.01.29v1.0
3 NA LC Liaison Jan	4 Staff Report April 2021_v1
5 SNARF_1	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.